#26/F 501.36931X00

Expedited Procedure Requested Amendment Under 37 CFR 1.116 Group 281&

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

IWASAKI, et al.

Serial No.:

09/255,856

Filed:

February 23, 1999

For:

SEMICONDUCTOR DEVICE WITH LAYERED

INTERCONNECT STRUCTURE

Group:

2813

Examiner:

S. Smoot

AMENDMENT AFTER FINAL REJECTION

Assistant Commissioner for Patents

Box AF

Washington, D.C. 20231

September 18, 2002

Sir:

In response to the Office Action mailed March 18, 2002, please amend the above-identified application as follows:

o.K. to

Enter

IN THE CLAIMS:

Please amend the claims presently in the application as follows:

10-1-02

30. (Twice Amended) A semiconductor device having a layered interconnection structure including a copper film formed overlying a surface of a semiconductor substrate, and having a dielectric film overlying the surface of the semiconductor substrate, wherein the layered interconnection structure includes the copper film and a neighboring film adjacent the copper film, the neighboring film

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